FORM HDP-1449 (Based on Form PTO-1449) **PATENT AND TRADEMARK OFFICE** **INFORMATION DISCLOSURE CITATION** (Use several sheets if necessary) Sheet 1 of 2	ATTORNEY DOCKET NO.	SERIAL NO.
	7784-000107/DVA	N/A
	APPLICANT	
	Blackmon et al.	
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	N/A	N/A

U.S. PATENT DOCUMENTS

Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
1.	RSH	3,456,134	07/15/1969	Ko		
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3.		3,553,588	01/05/1971	Honig		
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16.	↓	6,530,276	03/11/2003	Tajika et al.		

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Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translation Yes	No
1.	RSH	GB 2 026 284	04/17/1978	United Kingdom			
2.	↓	GB 2 064 883	11/27/1979	United Kingdom			

Examiner: Robert S. Heald Date Considered: 10/15/05

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	7784-000107/DVA	N/A
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	FILING DATE	GROUP
	N/A	N/A

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1.	RSat	Ibong Jung and Yongrae Roh, Design and fabrication of pieoceramic bimorph vibration sensors, Sensors and Actuators A69 (1998) 259-266.
2.		F.J. von Preissig and E.S. Kim, Topics in Finite-Element Modeling of Piezoelectric MEMS.
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Examiner: Robyn Steadd	Date Considered: 11/15/05

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